2D Materials

Room 122 - Session 2D+AP+EM+QS+SS+TF-TuM

2D Materials: Synthesis and Processing

Moderators: Jyoti Katoch, Carnegie Mellon University, **Huamin Li**, University at Buffalo-SUNY

8:00am **2D+AP+EM+QS+SS+TF-TuM-1 Tailored Growth of Transition Metal Dichalcogenides Monolayers and Their Heterostructures*, Andrey Turchanin,*** Friedrich Schiller University Jena, Germany **INVITED**

Two-dimensional materials (2D), their van der Waals and lateral heterostructures possess a manifold of unique electronic, optoelectronic and photonic properties which make them highly interesting for fundamental studies and technological applications. To realize this potential, their tailored growth as well as understanding of the role of their intrinsic defects and 2D-material/substrate interactions are decisive. In this talk, I will present an overview of our recent progress on the synthesis by chemical vapor deposition (CVD), material characterization and studying of fundamental electronic and photonic properties of 2D transition metal dichalcogenide (TMDs) including some applications in electronic and optoelectronic device as well as observing of new excitonic phenomena. A particular focus will be on the lateral heterostructures of TMD monolayers with atomically sharp boundaries and Janus TMDs.

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8:30am **2D+AP+EM+QS+SS+TF-TuM-3 High-Coverage MoS_2 Growth by Two-Step Annealing Process*, Shinichi Tanabe,*** *H. Miura,* Tokyo Electron Ltd., Japan*; N. Okada, T. Irisawa,* AIST, Japan*; Y. Huang, H. Warashina, A. Fukazawa, H. Maehara,* Tokyo Electron Ltd., Japan

Continuation of Moore's Law scaling requires thin channels in nanosheet field-effect transistor architecture. In this respect, transition-metal dichalcogenides (TMDs) are candidates for the channel material because TMDs are expected to show higher mobility than Si when thickness of the channel is extremely thin. Compatibility to Si nanosheet field-effect transistor fabrication process requires TMD/buffer multilayer film. To obtain such film, alternative preparation of TMD and buffer layers is necessary. Although high-quality TMD can be obtained on a buffer layer by transferring TMD from other substrates, development of a reliable transferring method is challenging. Thus, direct growth of a TMD on a buffer layer is preferable.

We report on a successful growth of high-coverage MoS_2 on SiO_2/Si substrate. The process starts with growing an initial film on SiO_2/Si substrate. Here, a continuous initial film can be easily grown by this process with high growth rate. Next, the initial film is sulfurized by a first annealing step followed by crystallization of the film by a second annealing step. The obtained film is a continuous layered film which was confirmed by cross-sectional TEM images. In addition, typical Raman spectra consisted of E_{2g} and A_{1g} peaks are observed in entire substrate which shows that MoS_2 is grown with high coverage. The difference of E_{2g} and A_{1g} peaks is about 21 cm^{-1}. These results indicate that the two-step annealing process is suitable for obtaining MoS_2 in large area.

8:45am **2D+AP+EM+QS+SS+TF-TuM-4 Anomalous Isotope Effect on the Optical Bandgap in a Monolayer Transition Metal Dichalcogenide Semiconductor*, Kai Xiao,*** Center for Nanophase and Materials Sciences Oak Ridge National Laboratory*; Y. Yu,* School of Physics and Technology, Wuhan University, China*; V. Turkowski,* Department of Physics, University of Central Florida*; J. Hachtel,* Center for nanophase and Materials Sciences Oak Ridge National Laboratory*; A. Puretzky, A. Ievlev, C. Rouleau, D. Geohegan,* Center for Nanophase and Materials Sciences Oak Ridge National Laboratory

Isotope effects on optical properties of atomically thin 2D materials have rarely been studied to date due to significant challenges posed by sample-to-sample variations resulting from defects, strain, and substrate interactions, complicating the interpretation of optical spectroscopic results. Here, we report a novel two-step chemical vapor deposition method to synthesize isotopic lateral junctions of MoS2, comprising monolayer single crystals with distinct isotopic regions. This method allowed the minimization of shifts in photoluminescence due to synthetic heterogeneities necessary to confirm the intrinsic isotope effect on the optical band gap of 2D materials. Raman measurements and temperature-dependent photoluminescence spectra revealed an unusual 13 (± 7) meV redshift as the Mo isotope mass increased in monolayer MoS2. This shift is distinct from the trend observed in conventional semiconductors and quantum wells (Si, GaAs, diamond, hBN, etc.). Our experimental characterization, along with time-dependent density-functional theory (TDDFT) and many-body second-order perturbation theory, disclosed that this anomalous shift in the optical band gap in 2D MoS2resulted from significant changes in the exciton binding energy induced by strong exciton-phonon scattering. This study provides fundamental insights into understanding the effect of exciton-phonon scattering on the optoelectronic properties of atomically thin 2D materials.

Synthesis science was supported by the U.S. Dept. of Energy, Office of Science, Materials Science and Engineering Division. This work was performed at the Center for Nanophase Materials Sciences, which is a DOE Office of Science User Facility.

9:00am **2D+AP+EM+QS+SS+TF-TuM-5 CVD Growth and Characterization of High-Quality Janus SeMoS and SeWS Monolayers*, Julian Picker,*** Friedrich Schiller University Jena, Germany*; M. Ghorbani-Asl,* Helmholtz Zentrum Dresden-Rossendorf, Germany*; M. Schaal, O. Meißner, F. Otto, M. Gruenewald, C. Neumann, A. George,* Friedrich Schiller University Jena, Germany*; S. Kretschmer,* Helmholtz Zentrum Dresden-Rossendorf, Germany*; T. Fritz,* Friedrich Schiller University Jena, Germany*; A. Krasheninnikov,* Helmholtz Zentrum Dresden-Rossendorf, Germany*; A. Turchanin,* Friedrich Schiller University Jena, Germany

Structural symmetry breaking of two dimensional (2D) materials leads to novel physical phenomena. For 2D transition metal dichalcogenides (TMDs) such symmetry breaking can be achieved by exchange of one chalcogen layer with another one. The resulting, so-called Janus TMD structure exhibits an intrinsic dipole moment due to the different electronegativity values of the top and bottom chalcogen layers. Since Janus TMDs do not exist as bulk crystals, they cannot be obtained by exfoliation and need to be synthesized. Recently, we developed a route to grow Janus SeMoS monolayers (MLs) by chemical vapor deposition (CVD). [1] In this approach $MoSe_2$ monolayers are firstly grown on Au foils and then sulfurized to exchange the bottom selenium layer with sulfur atoms. The formation of high-quality Janus SeMoS MLs and the growth mechanism are proven by Raman and X-ray photoelectron spectroscopy (XPS), photoluminescence measurements, transmission electron microscopy and density functional theory (DFT). Here we present an investigation down to the atomic scale of Janus SeMoS MLs grown on Au(111). From low-energy electron diffraction (LEED) and scanning tunneling microscopy (STM) measurements we determine experimentally the lattice parameters of Janus SeMoS for the first time. The obtained results are in good agreement with the respective DFT calculation. Based on the angle-resolved ultraviolet photoelectron spectroscopy (ARUPS) study, we also obtain the spin-orbit splitting value of the valence band at the K point. Moreover, applying the same approach, we grow and characterize Janus SeWS MLs and provide a comparative analysis with the Janus SeMoS system.

[1] Z. Gan, I. Paradisanos, A. Estrada-Real, J. Picker, C. Neumann, A. Turchanin *et al.*, *Chemical Vapor Deposition of High-Optical-Quality Large-Area Monolayer Janus Transition Metal Dichalcogenides*, Adv. Mater. **34**, 2205226 (2022).

9:15am **2D+AP+EM+QS+SS+TF-TuM-6 Location-Selective CVD Synthesis of Circular MoS_2 Flakes with Ultrahigh Field-Effect Mobility**, ***Chu-Te Chen**, A. Cabanillas, A. Ahmed, A. Butler, Y. Fu, H. Hui, A. Chakravarty, H. Zeng,* University at Buffalo-SUNY*; A. Yadav,* Applied Materials, Inc.*; H. Li,* University at Buffalo-SUNY*; K. Wong,* Applied Materials, Inc.*; F. Yao,* University at Buffalo-SUNY

Two-dimensional (2D) semiconducting transition metal dichalcogenides (TMDs) have been considered as promising channel material candidates for future nanoelectronics. The device performance has been significantly improved over the years due to the advancements in understanding of TMD materials, device design, and fabrication process. Despite the early success in demonstrating proof-of-concept devices, scalable and single-crystal growth of TMD films on suitable substrates remains a formidable roadblock to the development of commercially viable TMD-based nanoelectronics. To mitigate this problem, we exploit a controlled growth of high-quality TMD layers at desired locations and demonstrate excellent and consistent electronic properties in transistor device architectures. Taking MoS2 as an example, we develop a precursor-seeded growth strategy for the direct and site-specific synthesis on SiO2 substrates using chemical vapor deposition (CVD). By employing electron-beam lithography to pattern seed layers, precise nucleation and growth at designated positions are achieved. Through systematic exploration of CVD synthesis parameters, ordered arrays of circular MoS2 flakes are successfully grown with the MoO3 seeds serving as the nucleation sites. A comprehensive suite of microscopic/spectroscopic characterizations along with electrical measurements is utilized to analyze the microstructural and transport properties of the as-grown MoS2 flakes. The tri-layer circular MoS2 arrays possess an adjustable and uniform size and exhibit a consistent field-effect mobility up to ~20 cm2/V·s with Bi/Au electrode contacts. These findings showcase a technological breakthrough to 2D material synthesis and hold great promise for future integration of 2D materials in the next generation nanoelectronics.

9:30am **2D+AP+EM+QS+SS+TF-TuM-7 Optoelectronic Properties of Exfoliated and CVD Grown TMD Heterostructures**, ***Elycia Wright**, K. Johnson, S. Coye, M. Senevirathna, M. Williams,* Clark Atlanta University

Transition metal dichalcogenides (TMDs) have attracted significant attention due to their distinctive electronic band structures, which result in intriguing optoelectronic and magnetic properties such as direct bandgap in the visible-infrared range, large exciton binding energies and the presence of two intrinsic valley-contrasting quantities-the Berry curvature and the orbital magnetic moment. Researchers have recently shown interest in studying heterostructures made from different TMD materials. The idea is to combine these materials to create synergistic effects, which can result in even more exciting properties than those found in individual TMDs. For instance, MoS_2/WS_2 heterostructure can exhibit novel and enhanced optoelectronic performances, including bipolar doping and photovoltaic properties. TMD-based heterostructures may open many possibilities for discovering new physics and developing novel applications. While the science of TMDs and TMD-based heterostructures has made significant strides over the past decade, the field has not yet matured. Numerous challenges, particularly in realizing TMD-based practical applications, remain unresolved. This underscores the importance of our collective efforts in pushing the boundaries of this field.

Exfoliation is a common method for assembling TMD heterostructures, but it has limitations in producing TMD heterostructures on a large scale. The chemical vapor deposition (CVD) method can be used to grow TMD heterostructures on a large scale, which is required in massive device production. However, there are numerous challenges in growing high-quality TMD heterostructures with large areas by CVD, which need to be solved before TMD-based practical applications can be achieved. Our research will focus on the growth of heterostructures (MoS_2/WS_2) on various substrates (such as sapphire and SiO_2/Si) using chemical vapor deposition (CVD). We will explore different mechanisms to achieve large area heterostructures and compare the resulting optoelectronic properties with exfoliated heterostructures. The properties will be characterized using Raman and Fourier Transform infra-red (FTIR) spectroscopy and confocal laser optical microscopy.

9:45am **2D+AP+EM+QS+SS+TF-TuM-8 Pulsed Laser Deposited Amorphous Boron Nitride for 2D Materials Encapsulation**, ***Daniel T. Yimam**, S. Harris, A. Puretzky, I. Vlassiouk, G. Eres, K. Xiao, D. Geohegan,* Oak Ridge National Laboratory, USA

Recent advancements in 2D materials have opened new avenues in optoelectronics and microelectronics. However, their integration is hindered by challenges related to materials stability and degradation. Realizing the full potential of 2D materials requires synthesizing and functionalizing an encapsulation layer with desired properties. Recently amorphous boron nitride (aBN) has attracted attention as an ideal low-k material suitable for 2D electronics due to its effectiveness as a protective encapsulation layer.Unlike hexagonal boron nitride (h-BN), which requires high temperatures for deposition and poses challenges for large-area synthesis and integration, aBN can be deposited at significantly lower temperatures. This property makes aBN highly attractive and compatible for back-end-of-line (BEOL) processes in the semiconductor industry.

In this work, we demonstrate that pulsed laser deposition (PLD) enables the deposition of aBN with precise kinetic energy control of precursors, facilitating direct deposition onto 2D materials without significant defect formation. Various in situ plume diagnostics and monitoring tools during deposition were utilized to identify optimal deposition conditions, ensuring ideal kinetic energy ranges and accurate thickness control. This enhances the aBN as an effective encapsulation and barrier against 2D materials thermal degradation, while improving photoluminescence of encapsulated 2D materials. We believe our work significantly impacts future microelectronics by providing low thermal budget method for encapsulating 2D materials and understanding strain and defect evolution. Our work not only advances the practical applications of 2D materials but also paves the way for in situ experimental analysis and diagnostics in the field of material science.

This work was supported by the U.S. DOE, Office of Science, Materials Sciences and Engineering Division and the Center for Nanophase Materials Sciences, which is a DOE Office of Science User Facility.

Keywords: Pulsed Laser Deposition, Amorphous Boron Nitride, 2D Materials, Encapsulation, In Situ Diagnostics.

11:00am **2D+AP+EM+QS+SS+TF-TuM-13 Topotaxy for Compositional Variations of Transition Metal Dichalcogenides**, ***Matthias Batzill**,* University of South Florida

Topotaxy is a kind of solid-state reaction in which the product crystal is crystallographically related to the initial crystal. In 2D materials the initial crystal could be a single sheet or a few layers that are being reacted with same or dissimilar elements to produce novel 2D materials that may not exist in the bulk. Here we investigate such topotactical reactions for transition metal dichalcogenides (TMDs) by reacting them with vapor deposited transition metals. This can result in phase transformations of know layered materials, such as $PtTe_2$ +Pt => Pt_2Te_2 [1], new phases such as mirror twin grain boundary networks in $MoSe_2$ or $MoTe_2$ [2], or covalently linking bi-layer TMDs by intercalants of the same or different TMs [3]. The studies are performed on MBE grown TMDs and are further modified by post-growth reaction with TM. The resulting structures are characterized by surface probes, such as STM, photoemission, and LEED. In general, the open structure of many 2D materials make them ideal for topotaxy and provide an approach for modifying their composition and induce new properties. Moreover, it allows to locally modify an extended 2D sheet and thus produce in-plane heterojunctions between 'original' and modified 2D domains in a first step to create in-plane device structures.

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Post-Synthesis Modifications of Two-Dimensional MoSe2 or MoTe2 by Incorporation of Excess Metal Atoms into the Crystal Structure.

ACS Nano 12, 3975-3984 (2018)

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Formation of In-Plane Semiconductor–Metal Contacts in 2D Platinum Telluride by Converting PtTe2 to Pt2Te2.

Nano Letters 22, 9571-9577 (2022)

[3] V. Pathirage, S. Khatun, S. Lisenkov, K. Lasek, J. Li, S. Kolekar, M. Valvidares, P. Gargiani, Y. Xin, I. Ponomareva, M. Batzill.

2D Materials by Design: Intercalation of Cr or Mn between two VSe2 van der Waals Layers.

Nano Letters 23, 9579-9586 (2023)

11:15am **2D+AP+EM+QS+SS+TF-TuM-14 Solid State Reaction Epitaxy to Create van der Waals Heterostructures between Topological Insulators and Transition Metal Chalcogenides**, ***Salma Khatun**, O. Alanwoko, V. Pathirage, M. Batzill,* University of South Florida

Van der Waals (vdW) heterostructures have emerged as a promising avenue for exploring various quantum phenomena. However, the formation of these heterostructures directly is complicated, as individual materials could have different growth temperatures, and alloying can occur at the interface. We present an alternative process akin to a solid-state reaction to modify the surface layer of quantum materials and introduce new properties. Specifically, we used vapor-deposited transition metals (TMs), Cr and Mn, with the goal to react with Bi_2Se_3 and transform the surface layer into XBi_2Se_4 (X = Cr, Mn). Our results demonstrate that the TMs have a high selenium affinity that drives Se diffusion toward the TM. We found that when a monolayer of Cr is evaporated, the surface Bi_2Se_3 is reduced to Bi_2-layer, and a stable (pseudo) 2D $Cr_{1+\delta}Se_2$ layer is formed, whereas $MnBi_2Se_4$ phase is formed with a mild annealing for monolayer amount of Mn deposition.[1] However, this phase only occurs for a precise amount of initial Mn deposition. Sub-monolayer amounts dissolve into the bulk, and multilayers form stable MnSe adlayers. Our study highlights the delicate energy balance between adlayers and desired surface-modified layers that govern the interface reactions.[1] The success of obtaining the $MnBi_2Se_4$ septuple layer manifests a promising approach for engineering other multicomponent vdW materials by surface reactions.

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[1] S. Khatun, O. Alanwoko, V. Pathirage, C. C. de Oliveira, R. M. Tromer, P. A. S. Autreto, D. S. Galvao, and M. Batzill,*Adv. Funct. Mater.* **2024**, 2315112

11:30am **2D+AP+EM+QS+SS+TF-TuM-15 AVS National Student Award Finalist Talk: Quasi-Van Der Waals Epitaxial Growth of Thin γ'-Gase Films**, ***Mingyu Yu**[1], University of Delaware*; S. Law,* Pennsylvania State University

As an advanced two-dimensional (2D) layered semiconductor, GaSe has various appealing properties, such as rare intrinsic p-type conductivity, nonlinear optical behavior, high transparency in 650-180000nm, and a shift from an indirect-bandgap single-layer film to a direct-bandgap bulk material. These features make GaSe rich in potential in quantum photonic devices, field-effect transistors, photodetectors, etc. GaSe has a hexagonal crystal structure composed of Se-Ga-Ga-Se quadruple layers (QLs). Each QL is bonded by weak van der Waals (vdW) forces, enabling multiple polymorphs: ε-(2H), β-(2R), δ-(4H), and γ-(3R). They have identical non-centrosymmetric QL with a D_{3h} space group. Besides the four extensively explored polymorphs, a new polymorph, γ'-(3-R) GaSe, was proposed for the first time in 2018. γ'-GaSe is unique for its centrosymmetric D_{3d} QL (Fig. S1), for which γ'-GaSe is predicted to show intriguing properties compared to other polymorphs. However, there are few existing reports on the observation of γ'-GaSe due to its less-favorable formation energy. Moreover, the wafer-scale production of pure GaSe single crystal thin films remains challenging because of the coexistence of stable multiphases and polymorphs.

We developed a quasi-vdW epitaxial growth method to obtain high-quality pure γ'-GaSe nanometer-thick films on GaAs(111)B at a wafer scale. It results in GaSe thin films exhibiting a smooth surface with a root-mean-square roughness as low as 7.2 Å (Fig. S2a) and a strong epitaxial relationship with the substrate (Fig. S2b). More interestingly, we observed a pure γ'-polymorph using scanning transmission electron microscopy (Fig. S2c,d). Through density-functional theory analysis (Fig. S3), γ'-GaSe can be stabilized by Ga vacancies since its formation enthalpy tends to become lower than that of other polymorphs when Ga vacancies increase. We also observed that, unlike other GaSe polymorphs, γ'-GaSe is inactive in room-temperature photoluminescence tests. This may be related to its centrosymmetric QL structure, which we are exploring further. Meanwhile, we systematically studied the growth window for GaSe with high structural quality and identified that GaAs(111)B is more suitable than c-sapphire as a substrate for GaSe growth. Overall, this study advances the wafer-scale production of γ'-GaSe films, and elucidates a method for direct epitaxial growth of hybrid 2D/3D heterostructures with atomically sharp interfaces, facilitating the development of heterogeneous integration. In the future, we will focus on developing the properties and applications of γ'-GaSe, and delving into the understanding of the epitaxial growth mechanism.

11:45am **2D+AP+EM+QS+SS+TF-TuM-16 Investigation of Dry Transfer of Epitaxial Graphene from SiC(0001)**, ***Jenifer Hajzus**, D. Pennachio, S. Mack, R. Myers-Ward,* U.S. Naval Research Laboratory

Transfer of high-quality graphene from its growth substrate to substrates of technological interest can be necessary to enable its use in certain applications, however it remains challenging to achieve large-area transfer of graphene that is clean and intact. This work utilizes a dry transfer technique in which an adhesive metal stressor film is used to exfoliate epitaxial graphene (EG) from SiC(0001) [1]. In this method, the strain energy in the metal film must be high enough to allow for uniform exfoliation, but low enough such that self-exfoliation of graphene does not occur.

We investigate the dry transfer of monolayer EG (MEG) and hydrogen-intercalated, quasi-freestanding bilayer graphene (QFBEG) grown by sublimation of Si from nominally on-axis 6H-SiC(0001) in a CVD reactor in Ar ambient. A magnetron sputtered Ni stressor layer is used to exfoliate EG and transfer to GaAs, glass, and SiO_2/Si substrates. The Ar pressure during sputtering is found to impact the stress, film density, and roughness of the Ni film, as determined from wafer curvature and X-ray reflectivity (XRR) measurements. By using appropriate sputtering conditions, the Ni/graphene film exfoliates from the entire area of the SiC substrate with use of thermal release tape. Atomic force microscopy (AFM), scanning electron microscopy, Raman spectroscopy, x-ray photoelectron spectroscopy (XPS), and Nomarski microscopy are used to characterize the graphene. The Ni 2p peak was not detected in XPS of the transferred graphene after removal of the Ni film by etching in acid. Additionally, XPS revealed minimal oxide present at the graphene-GaAs interface, consistent with previous reports for this dry transfer method [2].

Raman spectroscopy mapping showed that predominately monolayer graphene is transferred from MEG, while predominately bilayer graphene is transferred from QFBEG. Raman spectroscopy of the SiC substrate after MEG exfoliation shows the $6\sqrt{3}$ buffer layer that forms during growth on SiC(0001) remains on the SiC substrate. Consequently, if there are regions of exposed $6\sqrt{3}$ buffer layer in the as-grown MEG on SiC, AFM shows that there are corresponding gaps in the transferred graphene film where the areas of exposed buffer layer do not transfer. The $6\sqrt{3}$ buffer layer is not present in QFBEG due to the hydrogen-intercalation process. It is found that the same Ni sputtering conditions that led to uniform exfoliation and transfer of MEG result in micron-scale tears in the Ni/QFBEG film. By lowering the strain energy in the sputtered Ni film, these tears can be reduced or eliminated.

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[2] Kim, H., *et al.*, ACS Nano, 15, 10587 (2021).

[1] **AVS National Student Award Finalist**

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Zeng, H.: 2D+AP+EM+QS+SS+TF-TuM-6, 2